IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

2A
8-3-01

Applicant:	Jurgensen et al.	Group Art Unit:	
Serial No.:			
Filed:		Attorney Docket No:	98-058/1D
For:	Confinement Device for Use in Dry Etching of Substrate Surface and Method of Dry Etching a Wafer Surface		

PRELIMINARY AMENDMENT

Hon. Commissioner of Patents and Trademarks
Washington, D.C. 20231

Dear Sir:

Prior to examination, please amend the application as follows:

IN THE CLAIMS

Please cancel claims 1-21.

05050.P004